



Top-Down Micro- or Nanofabrication and Its Applications

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Message from the Guest Editors

This Special Issue of *Micromachines* focuses on top-down micro- and nanofabrication. It will serve as a platform for communication of the latest developments and innovations in top-down micro- and nanofabrication and/or their applications. Researchers are invited to contribute with manuscripts that address the various challenges and opportunities in this field. Contributions covering the following topics, in addition to any related to the topic of the Special Issue, are welcome:

- Precision machining;
- Laser machining;
- Die manufacturing;
- New lithographical methods;
- Manufacturing system/equipment and tools;
- Surface properties and characterization;
- Reliability, consistency, and metrology;
- Semiconductor/optical/bio/medical applications;
- Precision molding and forming;
- Non-traditional manufacturing technology.





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Message from the Editor-in-Chief

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